PATENT ASSIGNMENT COVER SHEET

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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

CONVEYING PARTY DATA

Name	Execution Date
YUTAKA FUJINO	07/01/2019

RECEIVING PARTY DATA

Name:	TOKYO ELECTRON LIMITED	
Street Address:	3-1 AKASAKA 5-CHOME, MINATO-KU	
City:	TOKYO	
State/Country:	JAPAN	
Postal Code:	107-6325	

PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	16510519

CORRESPONDENCE DATA

Fax Number: (650)938-5200

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent

using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

Phone: 6503357291

Email: lburshteyn@fenwick.com

Correspondent Name: DOHYUN AHN

Address Line 1: 801 CALIFORNIA STREET Address Line 2: FENWICK & WEST LLP

Address Line 4: MOUNTAIN VIEW, CALIFORNIA 94041

ATTORNEY DOCKET NUMBER:	35470-44059/US	
NAME OF SUBMITTER:	DOHYUN AHN, REG. NO. 63,237	
SIGNATURE:	/Dohyun Ahn/	
DATE SIGNED:	07/12/2019	

Total Attachments: 2

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PATENT 505569859 REEL: 049744 FRAME: 0279

COMBINED ASSIGNMENT/DECLARATION (37 CFR 1.63)

For good and valuable consideration, the receipt of which is hereby acknowledged, the person(s) named below (referred to as "INVENTOR" whether singular or plural) has sold, assigned, and transferred and does hereby sell, assign, and transfer to TOKYO ELECTRON LIMITED, a Japanese corporation, having a place of business at 3-1 Akasaka 5-chome, Minato-ku, Tokyo 107-6325, Japan ("ASSIGNEE"), for itself and its successors, transferees, and assignees, the following:

- 1. The entire worldwide right, title, and interest in all inventions and improvements ("SUBJECT MATTER") that are disclosed in the following provisional application filed under 35 U.S.C. § 111(b), non-provisional application filed under 35 U.S.C. § 111(a), international application filed according to the Patent Cooperation Treaty (PCT), or U.S. national phase application filed under 35 U.S.C. § 371 ("APPLICATION"):
 - U.S. Patent Application No. 16/510,519 , entitled "METHOD AND APPARATUS FOR FORMING HARD MASK FILM AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICES" filed on July 12, 2019 , which claims priority from Japanese Patent Application No. 2018-139051 filed on July 25, 2018.
- 2. The entire worldwide right, title, and interest in and to:
 (a) the APPLICATION; (b) all applications claiming priority from the APPLICATION;
 (c) all provisional, utility, divisional, continuation, substitute, renewal, reissue, and other applications related thereto which have been or may be filed in the United States or elsewhere in the world; (d) all patents (including reissues and re-examinations) which may be granted on the applications set forth in (a), (b), and (c) above; and (e) all right of priority in the APPLICATION and in any underlying provisional or foreign application, together with all rights to recover damages for infringement of provisional rights.

INVENTOR agrees that ASSIGNEE may apply for and receive patents for SUBJECT MATTER in ASSIGNEE's own name.

INVENTOR agrees to do the following, when requested, and without further consideration, in order to carry out the intent of this Assignment: (1) execute all oaths, assignments, powers of attorney, applications, and other papers necessary or desirable to fully secure to ASSIGNEE the rights, titles and interests herein conveyed; (2) communicate to ASSIGNEE all known facts relating to the SUBJECT MATTER; and (3) generally do all lawful acts that ASSIGNEE shall consider desirable for securing, maintaining, and enforcing worldwide patent protection relating to the SUBJECT MATTER and for vesting in ASSIGNEE the rights, titles, and interests herein conveyed. INVENTOR further agrees to provide any successor, assign, or legal representative of ASSIGNEE with the benefits and assistance provided to ASSIGNEE hereunder.

INVENTOR represents that INVENTOR has the rights, titles, and interests to convey as set forth herein, and covenants with ASSIGNEE that the INVENTOR has not made and will not hereafter make any assignment, grant, mortgage, license, or other agreement affecting the rights, titles, and interests herein conveyed.

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Title:

METHOD AND APPARATUS FOR FORMING HARD MASK FILM AND METHOD FOR MANUFACTURING

SEMICONDUCTOR DEVICES

Filed:

RECORDED: 07/12/2019

July 12, 2019

Application No.:

16/510,519

INVENTOR grants the attorney of record the power to insert on this Assignment any further identification that may be necessary or desirable in order to comply with the rules of the United States Patent and Trademark Office for recordation of this document.

This Assignment may be executed in one or more counterparts, each of which shall be deemed an original and all of which may be taken together as one and the same Assignment.

DECLARATION (37 CFR 1.63) FOR UTILITY OR DESIGN APPLICATION USING AN APPLICATION DATA SHEET (37 CFR 1.76)

By signing below, INVENTOR further attests to the following:

- The APPLICATION was made or authorized to be made by INVENTOR.
- INVENTOR believes that INVENTOR is the original inventor or an original joint inventor of a claimed invention in the APPLICATION.
- INVENTOR acknowledges the duty to disclose to the United States Patent and Trademark Office all information known to INVENTOR to be material to patentability as defined in 37 CFR § 1.56, which for a continuation-in-part includes information known to INVENTOR to be material to patentability as defined in 37 CFR § 1.56 that became available between the filing date of the prior patent application and the National or PCT filing date of the continuation-in-part application.

INVENTOR hereby acknowledges that any willful false statement made in this declaration is punishable under 18 U.S.C. 1001 by fine or imprisonment of not more than five (5) years, or both.

Name and Signature	Date of Signature
Yutaka Thyina	2019/7/1
Yutaka FUJINO	

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